

SP03-077 *IFW*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: James G. Couillard, et al

Serial No: 10/622606

Examiner: Thien F. Tran

Filed: July 18, 2003

Group Art Unit: 2811

For: SILICON CRYSTALLIZATION USING
SELF-ASSEMBLED MONOLAYERSINFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. §§ 1.56, 1.97 – 1.98Mail Stop Amendment
Commissioner of Patents
Alexandria, VA 22313-1450

Dear Sir:

The Examiner's attention is hereby directed to the following reference(s) listed on the attached Form PTO-1449 for consideration in connection with the examination of the above-identified patent application. One copy of any non-US patent is enclosed.

Each of the enclosed reference(s) was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the enclosed documents constitute "prior art." If it should be determined that any of the submitted documents do not constitute "prior art" under United States law, applicant(s) reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

Applicant(s) further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the enclosed references, should one or more of the references be applied against the claims of the present application.

Respectfully submitted,

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Date: 4/7/05

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Mail Stop Amendment, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on APRIL 7, 2005
Date of Deposit

Thomas R. BeallName of applicant, assignee, or
Registered Representative

Signature

4/7/05

Date of Signature

FORM PTO-1449 (MODIFIED)

APR 11 2005

ATTORNEY DOCKET NO.

SP03-077

SERIAL NO.

10/622606

LIST OF PATENTS AND
PUBLICATIONS
FOR APPLICANTS INFORMATION
DISCLOSURE STATEMENT

APPLICANT: James G. Couillard, et al.

FILING DATE July 18, 2003

GROUP: 2811

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
	AA	5,352,485	10/4/94	DeGuire et al	427	226	4/8/93
	AB	5,751,018	5/12/98	Alivisatos et al	257	64	4/29/94
	AC	6,464,780	10/15/02	Mantl et al	117	90	
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-Class	Translation Yes	No
	AL	WO03/057949	7/17/03	PCT	C30B	7/04	X	
	AM	EP0598361	5/25/94	Europe	C23C	16/02	X	
	AN							
	AO							
	AP							
	AQ							

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	AR	Niesen, et al.; "Chemical liquid deposition of gallium nitride thin films on siloxane-anchored self-assembled monolayers"; Materials Chemistry and Physics 73 (2002) pages 301-305.
	AS	
	AT	

EXAMINER:

DATE CONSIDERED:

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.